

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	2533	(reference adj2 output) same (control\$5 adj2 output)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 15:33
L2	92468	MEMS (microelectromechanical micro-electro-mechanical (micro adj electro adj mechanical) (micro adj mechanical) micro-mechanical micromechanical)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 15:33
L3	0	L2 same L1	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 15:33
L4	12	1 and 2	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 15:34
L5	1346	(reference adj2 output) with (control\$5 adj2 output)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:02
L6	492987	(tim\$3 adj3 signal\$1)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:02
L7	52	5 same 6	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:03
L8	0	2 and 7	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:03
L9	0	charg\$3 same 7	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:03
L10	52	output same 7	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:03
L11	325338	electrostatic\$4 electro-static\$4	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:04

L12	0	L11 same L7	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/02 16:04
S1	92302	MEMS (microelectromechanical micro-electro-mechanical (micro adj electro adj mechanical) (micro adj mechanical) micro-mechanical micromechanical)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:03
S2	90279	(moving moveable movable) adj2 (wafer plate board substrate)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:04
S3	143373	(fixed stationary) adj2 (wafer plate board substrate)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:04
S4	325029	electrostatic\$4 electro-static\$4	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:06
S5	52	S1 same S2 same S3 same S4	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:06
S6	3286635	(gap opening)	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:06
S7	19	S5 same S6	US- PGPUB; USPAT; EPO; JPO	OR	ON	2009/04/01 20:07

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